

SUBSTRATE FILM THICKNESS MEASUREMENT METHOD,  
SUBSTRATE FILM THICKNESS MEASUREMENT APPARATUS  
AND SUBSTRATE PROCESSING APPARATUS

ABSTRACT OF THE DISCLOSURE

5        A jet of water in a cylindrical form is supplied from  
a jet nozzle onto a measurement surface of a substrate to  
form a column of the water extending between the nozzle and  
the measurement surface. Light is emitted from an  
irradiation fiber and transmitted through the column of  
10      water to the measurement surface. The light reflected by  
the measurement surface is received by a light-receiving  
fiber through the column of water. A measurement  
calculation unit measures the thickness of a film formed on  
the substrate, based on the intensity of the reflected  
15      light.